

LEYBOLD OPTICS IBS series

Technical data

Systems			LO IBS 1400	LO IBS 1600
Coating Technology			Ion beam sputtering with 3-Grid RF source	
Systems	High precision (HP)	Laser application	1 x diameter 400 mm substrate	1 x diameter 600 mm substrate
		Telecom application	1 x diameter 304 mm (12") substrate	
	High throughput (HT)	Medical/Metrology / Microscopy	4 x diameter 350 mm substrate	
Coating materials			Metallic / dielectric material	
Target configuration			3 – Target assembly	
Sources		Sputter source	3 Grid RF 220 mm	
		Assist source	LION 100 RF (Single Grid)	
Layer monitoring		Time control	Yes	
		Optical monitoring	LEYBOLD OPTICS OMS 5100 Optional: LEYBOLD OPTICS BBM	
Vacuum system		Pre-vacuum pump	Oil-free pump system	
		High-vacuum pump	Cryo-pump system	Turbo molecular pump system
Floor space		[m]	3.3 x 5.1 x 2.9	3.5 x 5.4 x 2.9
		[inch]	130 x 200 x 114	134 x 212 x 114
Site requirements		Electric power	60 kVA	66 kVA
		Line voltage	400 V AC, 50/60 Hz	
		System weight	6700 kg	7000 kg